

QFP Assembly Generic QC Flow & Control Plan

| QFP Assembly Generic QC Flow & Control Plan | | | | | | |
|---|------------------------------|--|---|--|--|--|
| Process Flow | Operation | Function Visual shock for broken | Frequency | Sample size | | |
| | | Visual check for broken wafer | Every wafer | Whole area of wafer back | | |
| | Incoming Wafer Inspection | wafer backside check for crack and scratch | Every wafer | 5 wafer | | |
| | | Inspection for die defect | Every wafer | 75ea/5 wafers; 9points per wafer | | |
| | Backgrinding | Backgrind thickness | Every setup | 5 data. 1 wafer | | |
| | | Wafer backside roughness measure | 1x/shift/machine | 1 pcs wafer | | |
| | | TTV | Every setup | 1 pcs wafer | | |
| | Wafer saw | Visual check | 1x/shift/every change device | 50 units | | |
| | | Saw Line | Between 5th to 15th line in wafer | Every wafer | | |
| \Diamond | 2/0 QC Gate | Visual defects | Every wafer lot | 125 dies | | |
| | | Visual inspection | Every set-up | 2ea | | |
| | | Die backside inspection | Every setup, Every 8 hrs / MC | 5ea, (2ea monitor) | | |
| | | Die tilt Fillet height | Every setup, Every 8 hrs / MC Every setup, Every 8 hrs / MC | 2ea 2ea | | |
| | | Epoxy coverage | Every setup, Every 8 hrs / MC | 2ea | | |
| | 5 | Die backside chip | | | | |
| | Die Attach | measurement | Every setup | 2ea | | |
| | | Die placement | Every setup, Every 8 hrs / MC | 2ea | | |
| | | p.200o | | | | |
| | | Epoxy void | Every setup, Every 12 hrs / MC | 2ea, size<100 units 10% lot size; >100 units 10 good dice | | |
| | | Bondline thickness | Every setup, Every 8 hrs / MC | 2ea | | |
| | Die Attach Cure | Die shear | per oven/12hours | 2ea | | |
| | Die Atlach Cure | Epoxy void | Per day/mc | 1 strip | | |
| | Plasma clean | Contact angle measurement on die surface | 1x / 1day / machine | 3ea | | |
| | | Wire pull test | 1x/shift/machine | 10 wires | | |
| 40 | Wire Bond | Ball shear test | 1x/shift/machine | 10 balld | | |
| | | Cratering | Every setup | 1 ea | | |
| | | | | 125ea: Lot size≤3200, | | |
| $\langle \rangle$ | 3/0 QC Gate | Visual inspection | Per lot | 200ea: 3200 <lot size≤10000<="" th=""></lot> | | |
| | | | | 315ea: 10000 < Lot size≤35000 500ea: Lot size>35000 | | |
| | Plasma clean | Contact angle measurement on die surface | 1x / 1day / machine | Every machine | | |
| | | Visual inspection | Every setup | 1st good shot | | |
| | | warpage | Every mold die set-up | 1st good shot,2unit/strip | | |
| | Mold | Package thickness | Every mold die set-up | 1st good shot,1unit/strip | | |
| | | | 1X/mold die/MC/shift Every mold die set-up, | 1X/mold die/MC/shift (monitor) | | |
| | | leadframe off centering Temperature / time | 1x/day/machine (for the day w/o setup buyoff) 3 oven/1shift | 5 unit in 1 shot Nil | | |
| | Post mold cure | Warpage | Per pkg type/size/day | 2 units | | |
| 1 T | | Delamination | 3 ovens/ shift | 1 strip/Oven | | |
| | | Visual defects | After each change of trim die set/ PM & | the first strip, | | |
| () | Trim | Micro defects | machine repaired; at least once per shift for machines that | 3 units/strip, 1 strips; 1 unit (monitor) | | |
| | 111111 | dambar instrusion/protrusion | After each change of trim die set/ PM & machine repaired. | 5 units/strip,1 strip | | |
| | Debleed | visual inspection | 1x / shift / Machine | 5 strips | | |
| | Peniega | | 1x / sniπ / Machine After equipment repair or PM,each time 3 | | | |
| | | visual inspection | strips. | 3 strips | | |
| $H() $ | | composition | 3 kinds of pkg size, 3 lots/shift, each time 3 | 3 strips , 12 readings | | |
| | Plating | plating thickness | strips. | 3 strips , 12 readings | | |
| $ \mathcal{A}() $ | | | When machine idle,At least 1 lots/shift do | | | |
| | | solderability test | Per day/bathe | 5 units | | |
| | | ion contamination | Per bath / week | 3 strips | | |
| | | Visual inspection | Every setup; | First strip; | | |
| | Laser marking | Engraving depth | 1X/Shift/Machine Every setup | 1 strips 5 points of 1st strip | | |
| | | visual inspection | After each change of form die set/die set | 5 units; 1 tray | | |
| | F- | micro defects | cleaning/PM & machine repaired; 1x/shift/machine | 5 units | | |
| | Form | co-planarity | | 5 units | | |
| | | dimension check | After each change of form die set/die set cleaning/PM & machine repaired; | 5 units | | |
| | Florida 100 | External width,Stand off Visual defects | 1x/shift/machine Per sub-lot | 5 units AQL 0.04 | | |
| | Final visual QC Gate | Side defects visual | Per sub-lot | 10 units | | |
| | Odle | Reject verification | Per sub-lot | 5 units | | |

Test Generic QC Flow & Control Plan

| | rest deficit do now a control rian | | | | |
|-----------------------|------------------------------------|-----------------|-----------|-------------------------------------|--|
| Process Flow | Process | Function | Frequency | Sample size | |
| | Electrical Test | EQA buyoff | Every lot | per AQL sampling plan, min 0.065 | |
| Ĭ | Electrical rest | EQA Duyon | Every lot | 0.065 | |
| | OQA | Visual defects | Every lot | 315units/lot | |
| $\overline{\bigcirc}$ | Pack | Document, label | Every | lot | |